Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application.

Listing of Claims:

Claim 1 (original): A method for replacing a microelectronic spring contact bonded to a terminal of a substrate, the method comprising:

removing the microelectronic spring contact from the terminal;

aligning a replacement spring contact over the terminal, the replacement spring contact comprising a base configured to fit over the terminal, and at least one resilient cantilever arm extending from the base, whereby the replacement spring contact is aligned so that the base of the replacement spring contact is opposite to the terminal and the resilient cantilever arm extends away from the substrate; and

bonding the replacement spring contact to the terminal.

Claim 2 (original): The method of Claim 1, wherein the removing step further comprises cutting the microelectronic spring contact in two adjacent to the terminal.

Claim 3 (original): The method of Claim 1, wherein the bonding step further comprises depositing a bonding material between the terminal and the replacement spring contact.

Claim 4 (original): The method of Claim 3, wherein the bonding step further comprises depositing the bonding material consisting essentially of a solder paste.

Claim 5 (original): The method of Claim 4, wherein the bonding step further comprises applying an electric current across the base of the replacement spring contact using an electrode.

Claim 6 (original): The method of Claim 1, wherein the aligning step further comprises aligning the replacement spring contact having a core of resilient material coated with a conductive material.

Claim 7 (original): The method of Claim 6, wherein the aligning step further comprises aligning the replacement spring contact having the core made of nickel-cobalt alloy.

Claim 8 (original): The method of Claim 6, wherein the aligning step further comprises aligning the replacement spring contact having the core coated with gold or a gold alloy.

Claim 9 (original): The method of Claim 1, wherein the aligning step further comprises aligning the replacement spring contact having the base with at least two legs extending from the base in a direction opposite to the cantilever arm.

Claim 10 (original): The method of Claim 1, wherein the aligning step further comprises aligning the replacement spring contact whereby the at least two legs are on opposite sides of a stub protruding from the terminal.

Claim 11 (currently amended): A method for forming on a substrate a microelectronic spring contact comprising a base at a bottom portion of the spring contact and a tip at a top portion of the spring contact, the method comprising:

depositing a release layer over a substrate;

depositing a seed layer of conductive material over the release layer:

depositing a layer of sacrificial layer over the seed layer;

patterning the sacrificial layer to form at least one recess exposing the seed layer in the shape of the a side profile of a microelectronic the microelectronic spring contact;

filling depositing a contact structure material in the at least one recess with a resilient material;

removing the layer of sacrificial layer to reveal a microelectronic spring contact comprising a base and an arm extending from the base, wherein the base and the arm are adhered along sides thereof to the substrate and an axis of the microelectronic spring contact extending between a distal tip of the arm and the base is parallel to the substrate; and

releasing the microelectronic spring contact structure material entirely from the substrate.

Claim 12 (currently amended): The method of Claim 11 31, wherein the first depositing step further comprises depositing the release layer consisting essentially of comprises aluminum.

Claim 13 (currently amended): The method of Claim 11 31, wherein the second depositing step further comprises depositing the seed layer consisting essentially of comprises copper.

Claim 14 (currently amended): The method of 11 31, wherein the third depositing step further emprises depositing the layer of sacrificial layer consisting essentially of an SU-8 comprises a photoresist.

Claim 15 (currently amended): The method of Claim 11, wherein the filling step of depositing a contact structure material further comprises electroplating the resilient contact structure material in the at least one recess.

Claim 16 (currently amended): The method of Claim 11, wherein the filling step further comprises electroplating a the contact structure material comprises nickel-cobalt material in the at least one recess.

Claim 17 (original): The method of Claim 11, further comprising depositing a conductive material over the microelectronic spring contact after the releasing step.

Claim 18 (original): The method of Claim 17, wherein the depositing a conductive material step further comprises plating the conductive material consisting essentially of a layer of gold.

Claim 19 (currently amended): The method of Claim 11, wherein the side profile is such that an axis extending between the tip and the base is substantially parallel with a surface of the substrate,

the method further comprising bonding the base of the microelectronic spring contact to a second substrate after the releasing step, wherein the microelectronic spring contact is oriented so that the axis the spring contact extends away from a surface of the second substrate.

Claim 20 (original): The method of Claim 19, wherein the bonding step further comprises bonding the base to a terminal of the second substrate.

Claim 21 (original): A method for repairing a microelectronic spring contact comprising a beam bonded to at least one post that is in turn bonded to a terminal of a substrate, the method comprising:

removing the beam from the at least one post, thereby providing a removed beam; removing at least a portion of the at least one post from the terminal;

aligning a replacement post piece over the terminal, the replacement post piece comprising a base configured to fit over the terminal, and at least one replacement post extending upwards from the base, whereby the replacement post piece is aligned so that the base of the replacement post piece is opposite to the terminal and the at least one replacement post extends away from the substrate;

bonding the replacement post piece to the terminal; and

bonding a replacement beam to the at least one replacement post, wherein the replacement beam is selected from a group consisting of the removed beam and a new beam essentially identical to the removed beam.

Claim 22 (original): The method of Claim 21, wherein the first removing step further comprises de-soldering the beam from the at least one post.

Claim 23 (original): The method of Claim 21, wherein the second removing step further comprises cutting the at least one post in two adjacent to the terminal.

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Claim 24 (original): The method of Claim 21, wherein the first bonding step further comprises applying a solder paste to the terminal.

Claim 25 (original): The method of Claim 24, wherein the first bonding step further comprises applying an electric current across the replacement post piece to activate the solder paste.

Claim 26 (original): The method of Claim 21, wherein the second bonding step further comprises applying a solder paste to the at least one replacement post.

Claim 27 (original): The method of Claim 26, wherein the first bonding step further comprises applying an electric current across a portion of the replacement beam to activate the solder paste.

Claim 28 (original): The method of Claim 21, wherein the aligning step further comprises aligning the replacement post piece made of nickel-cobalt alloy.

Claim 29 (original): The method of Claim 21, wherein the aligning step further comprises aligning the replacement post piece having a base with at least two legs extending from the base in a direction opposite to the at least one post.

Claim 30 (original): The method of Claim 29, wherein the aligning step further comprises aligning the replacement post piece whereby the at least two legs are on opposite sides of a stub protruding from the terminal.

Claim 31 (new): The method of claim 11 further comprising:

depositing a release layer on said substrate; and
depositing a seed layer on said release layer,
wherein said sacrificial layer is deposited on said seed layer.

Claim 32 (new): The method of claim 11, wherein a first portion of said at least one recess defines said base of said of said spring contact and a second portion of said at least one recess defines said tip of said spring contact, wherein said first portion and said second portion of said at least one recess are disposed in a plane that is substantially parallel to a surface of said substrate.

Claim 33 (new): A method of forming an interconnect element, said interconnect element configured to be attached to a final substrate in a first orientation with respect to a surface of said final substrate, said method comprising:

providing a sacrificial substrate; and

forming said interconnect element on said sacrificial substrate in a second orientation with respect to a surface of said sacrificial substrate,

wherein said second orientation is different than said first orientation.

Claim 34 (new): The method of claim 33, wherein:

in said first orientation, said interconnect element is upright with respect to said surface of said final substrate; and

in said second orientation, said interconnect is on one of its sides with respect to said surface of said sacrificial substrate.

Claim 35 (new): The method of claim 33, wherein said interconnect element comprises a base and a tip, and:

in said first orientation, said base is attached to said final substrate, and said tip is spaced apart from said final substrate; and

in said second orientation, said base and said tip are disposed in a plane that is substantially parallel to said surface of said sacrificial substrate.



Claim 36 (new): The method of claim 33, wherein said interconnect element comprises a base and a tip, and

in said first orientation, an axis extending from said base to said tip extends away from said surface of said final substrate; and

in said second orientation, said axis is substantially parallel to said surface of said sacrificial substrate.

Claim 37 (new): The method of claim 33 further comprising releasing said interconnect element from said sacrificial substrate.

Claim 38 (new): The method of claim 37, wherein said step of providing a sacrificial substrate comprises providing a sacrificial substrate having a release layer.

Claim 39 (new): The method of claim 38, wherein said step of releasing said interconnect element comprises removing said release layer.

Claim 40 (new): The method of claim 37 further comprising attaching said released interconnect element to said final substrate in said first orientation.

Claim 41 (new): The method of claim 33, wherein said step of forming said interconnect element comprises depositing material in a patterned sacrificial layer.

Claim 42 (new): The method of claim 41, wherein said sacrificial layer comprises a photoresist.

Claim 43 (new): The method of claim 41, wherein said sacrificial layer is patterned to define a side profile of said interconnect element.

Claim 44 (new): The method of claim 41, wherein the step of depositing material comprises electroplating said material.

Claim 45 (new): The method of claim 44, wherein said step of providing a sacrificial substrate further comprises providing a sacrificial substrate having a seed layer.

Claim 46 (new): The method of claim 45, wherein said step of electroplating said material comprises electroplating said material onto said seed layer.

Claim 47 (new): The method of claim 33 further comprising forming a plurality of said interconnect elements on said sacrificial substrate.

Claim 48 (new): The method of claim 47, wherein said plurality of interconnect elements are tied together.

Claim 49 (new): The method of claim 48, wherein said plurality of interconnect elements are tied together by a tie bar and tabs.

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